ANSI/ TAG to ISO/TC 172/SC 9 Annual Report for 2012

Prepared by Thomas Lieb, SC9 US Delegation Leader

SC 9 - Electro-optical Systems (Lasers)

- WG1 - Terminology and Test Methods for Lasers
- WG2 - Interfaces and System Specifications for Lasers
- WG3 - Safety
- WG4 - Laser Systems for Medical Applications
- WG5 - Laser Systems for General Applications
- WG6 - Optical Components and their Test Methods
- WG7 - Electro-optical Systems Other than Lasers

Parent Organization ANSI

ISO/TC172/SC9 meetings in 2012

ISO/TC 172/SC 9- 1, held in Nara/Japan on 2012-02-21 and 2012-02-23
meeting was attended by 32 participants from 8 P-members.

WG1 -	1, held in conjunction with ISO/TC 172/SC9, Nara Japan,
WG2 -	dormant
WG3 -	1, held in conjunction with IEC/TC 76/JWG 10, Didcot, UK
WG4 -	1, held in conjunction with ISO/TC 172/SC9, Nara Japan
WG5 -	dormant
WG6 -	1, held in conjunction with ISO/TC 172/SC9, Nara Japan
WG7 -	work Conducted prior to Nara, and report submitted to plenary

Work of SC7 in 2011

During the course of the year the work of the various working groups, as represented by the documents prepared and voted on, (By date/ Document Number) was as follows:
N459 ISO Comments template 5860 sc9N459.pdf
N459: ISO/DTS 17915: Optics and photonics - Measuring method of laser diodes for sensing.
N458 ISO Comments template 5859 sc9N458.pdf
N458: ISO/CD 17901-2: Optics and photonics - Holography - Part 2: Methods for measurement of hologram recording characteristics.
N457 ISO Comments template 5858 sc9N457.pdf
N457: ISO/CD 17901-1: Optics and photonics - Holography - Part 1: Methods of measuring diffraction efficiency and associated optical characteristics of holograms.
N456 ISO Comments template 5857 sc9N456.pdf
N456: ISO/CD 11151-2: Lasers and laser-related equipment - Standard optical components - Part 2: Components for the infrared spectral range.
N455 ISO Comments template 5856 sc9N455.pdf

N455: ISO/CD 11151-1: Lasers and laser-related equipment - Standard optical components - Part 1: Components for the UV, visible and near-infrared spectral ranges.

Proposed US ballot

Proposed US comments

2012 Systematic Review of ISO 11810-2:2007

Ballot 5793 sc9SR2012ISO11810_2.pdf

(2012 Systematic Review of ISO 11810-2:2007 (vers 2) Lasers and laser-related equipment -- Test method and classification for the laser-resistance of surgical drapes and/or patient-protective covers -- Part 2: Secondary ignition

Proposed US ballot

Proposed US comments

2012 Systematic Review of ISO 11810-1:2005

Ballot 5792 sc9SR2012ISO11810_1.pdf

2012 Systematic Review of ISO 11810-1:2005 (vers 2) Lasers and laser-related equipment -- Test method and classification for the laser resistance of surgical drapes and/or patient protective covers -- Part 1: Primary ignition and penetration

Proposed US ballot

2012 Systematic Review of ISO 11145:2006

Ballot 5791 sc9SR2012ISO11145.pdf

2012 Systematic Review of ISO 11145:2006 (Ed 3, vers 2) Optics and photonics -- Lasers and laser-related equipment -- Vocabulary and symbols

N454 ISO Comments template 5785 sc9N454.pdf

N454: ISO/WD 13142: Optics and photonics — Electro-optical systems — Cavity ring-down technique for high reflectance measurement (for comment)

N453 5652 sc9N453.pdf

N453: (CEN CONSULTANT) Enquiry assessment of prEN ISO 11553-3.

N452 639 sc9N452.pdf

N452: REPORT OF VOTING ON ISO/DIS 11553-3.2: Safety of machinery -- Laser processing machines -- Part 3: Noise reduction and noise measurement methods for laser processing machines and hand-held processing devices and associated auxiliary equipment (accuracy grade 2).

N451 5638 sc9N451.pdf

N451: 2012 Report of Secretariat presentation at Nara meeting.

N450 5637 sc9N450.pdf

N450: Report on the plenary meetings of ISO/TC 172/SC 9 in Nara/Japan on 2012-02-21 and 2012-02-23. (Comments by 6/21/12)

N449 5596 sc9N449.pdf

N449: Result of voting on NWIP: ISO 13142 Electro-optical systems – Cavity ring-down technique for high reflectance measurement.

N448 5595 sc9N448.pdf

N448: Result of voting on NWIP: ISO 17935 Optics and photonics — Lasers and laser-related equipment — Specification of surface cleanliness.

N447 5594 sc9N447.pdf

N447: Result of voting on NWIP: ISO 17901-2 Optics and photonics - Holography - Part 2: Methods for measurement of hologram recording characteristics.

N446 5593 sc9N446.pdf

N446: Result of voting on NWIP: ISO 17901-1 Optics and photonics - Holography - Part 1: Methods of measuring diffraction efficiency and associated optical characteristics of holograms.

N445 5592 sc9N445.pdf

N445: Result of voting on NWIP: ISO/TS 17915 Optics and photonics - Measuring method of semiconductor lasers for sensing.

US position: Agree, no comments

ISO/DIS 11553-3.2 ISO Comments template 5585 sc9DIS11553_3_2.pdf

ISO/DIS 11553-3.2: Safety of machinery — Laser processing machines — Part 3: Noise reduction and noise measurement methods for laser processing machines and hand-held processing devices and associated auxiliary equipment (accuracy grade 2).

Report of voting 5584 sc9DIS11553_3RepVote.pdf

Report of voting on ISO/DIS 11553-3: Safety of machinery — Laser processing machines — Part 3: Safety requirements for noise reduction and noise measurement methods for laser processing machines and hand-held processing devices and associated auxiliary equipment (accuracy grade 2). (includes Explanatory Report)

N444 5581 sc9N444.pdf

N444: *REVISED* Notice of meeting/Draft agenda for TC172/SC9 meetings in Nara, Japan (Feb 21-23, 2012).

N443 5572 sc9N443.pdf

N443: **Revised practical hotel information for the next meetings of ISO/TC 172/SC 9**.

N442 5564 sc9N442.pdf

N442: RESULT OF SYSTEMATIC REVIEW OF ISO STANDARD: ISO 14880-1 Optics and photonics -- Microlens arrays -- Part 1: Vocabulary.

N441 5563 sc9N441.pdf

N441: RESULT OF SYSTEMATIC REVIEW OF ISO STANDARD: ISO 14881 Integrated optics -- Interfaces -- Parameters relevant to coupling properties.

N440 5562 sc9N440.pdf

N440: RESULT OF SYSTEMATIC REVIEW OF ISO STANDARD: ISO 11807-2 Integrated optics -- Vocabulary -- Part 2: Terms used in classification.

N439 5561 sc9N439.pdf

N439: RESULT OF SYSTEMATIC REVIEW OF ISO STANDARD: ISO 11807-1 Integrated optics -- Vocabulary -- Part 1: Basic terms and symbols.

N438 5549 sc9N438.pdf

N438: NOTICE OF MEETING / DRAFT AGENDA (includes Practical and Registration information) for the next meetings of ISO/TC 172/SC 9 and its working groups in Nara/Japan in February 2012. (

N437 5548 sc9N437.pdf

N437: Report of Secretariat ISO/TC 172/SC 9 Electro-optical systems Reporting period 2010-11 to 2011-11.

N435 Ballot 5539 sc9N435.pdf
N435: NWIP: Optics and photonics — Lasers and laser-related equipment — Specification of surface cleanliness.Proposed US Ballot
N434 Ballot 5534 sc9N434.pdf
N434: NWIP: ISO/TS xxxxx: Optics and photonics — Measuring method of semiconductor lasers for sensing. Proposed US Ballot

Meetings for 2013

ISO/TC172/SC9, it working groups and project groups, will meet at the premises of NIST in **Gaithersburg, MD, USA, 2013 Sept. 9 - 11**.
ISO/TC 172/SC 9/WG 3 will meet with counterpart **IEC/TC 76/JWG 10** in Frankfurt, Germany, September 24, 2013